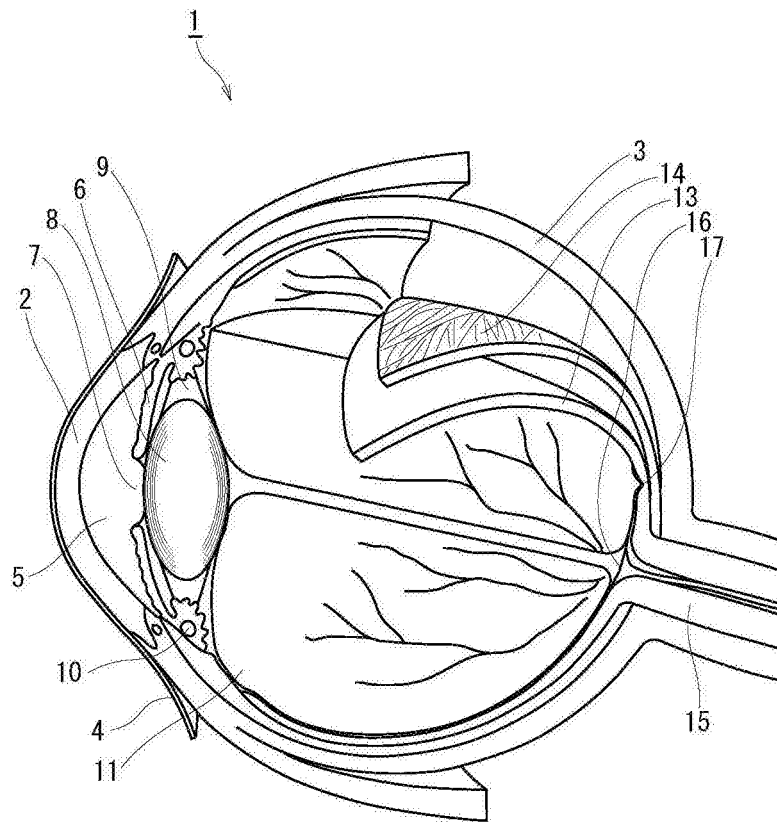
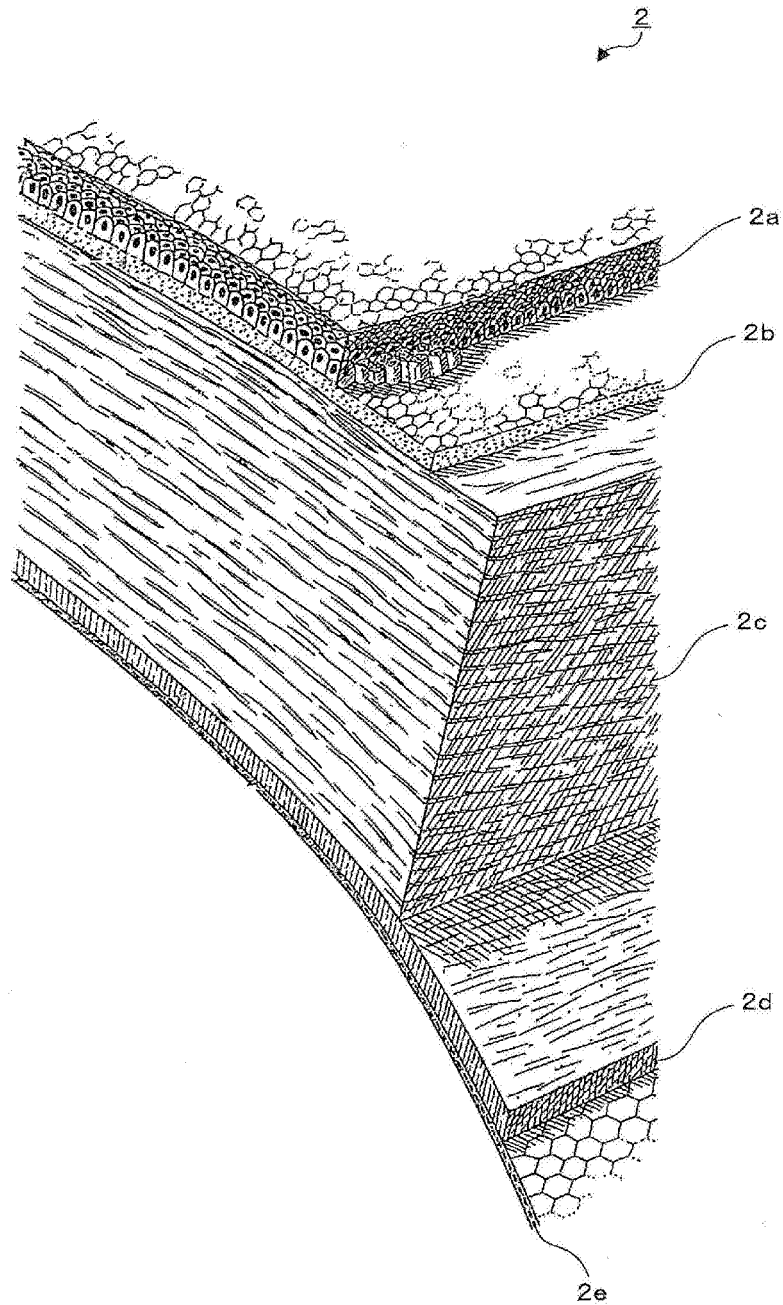


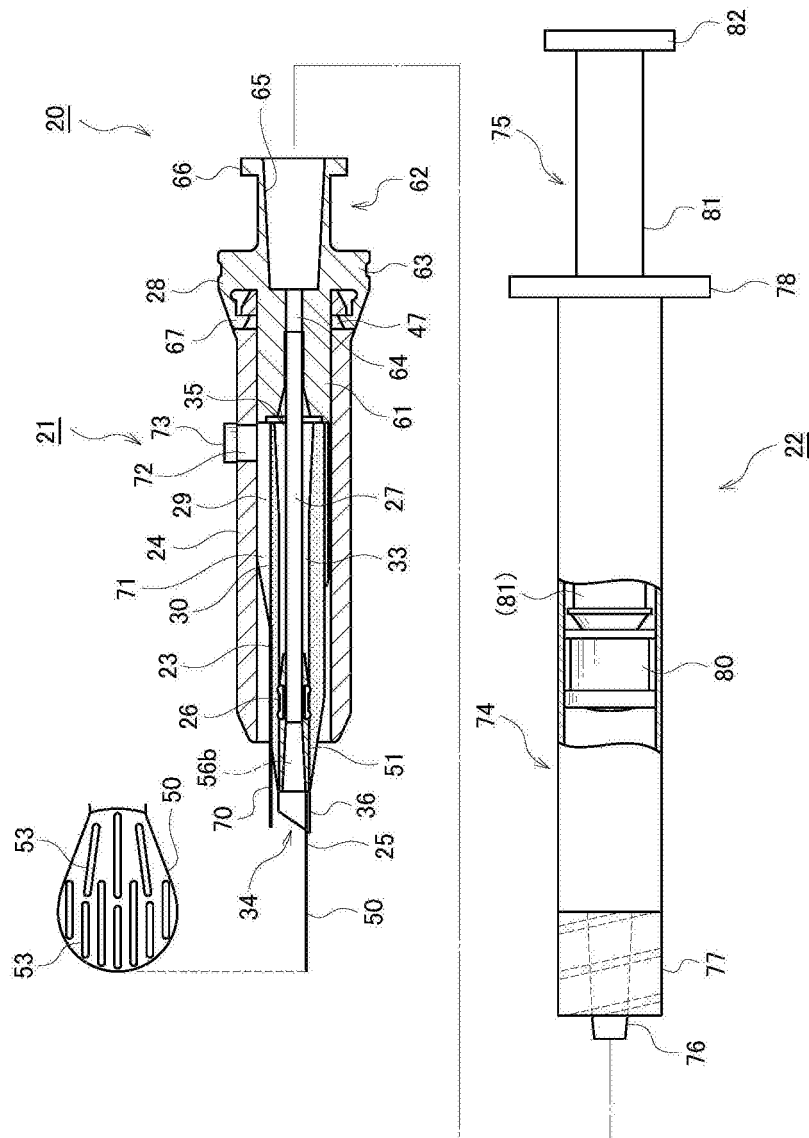
[図1]



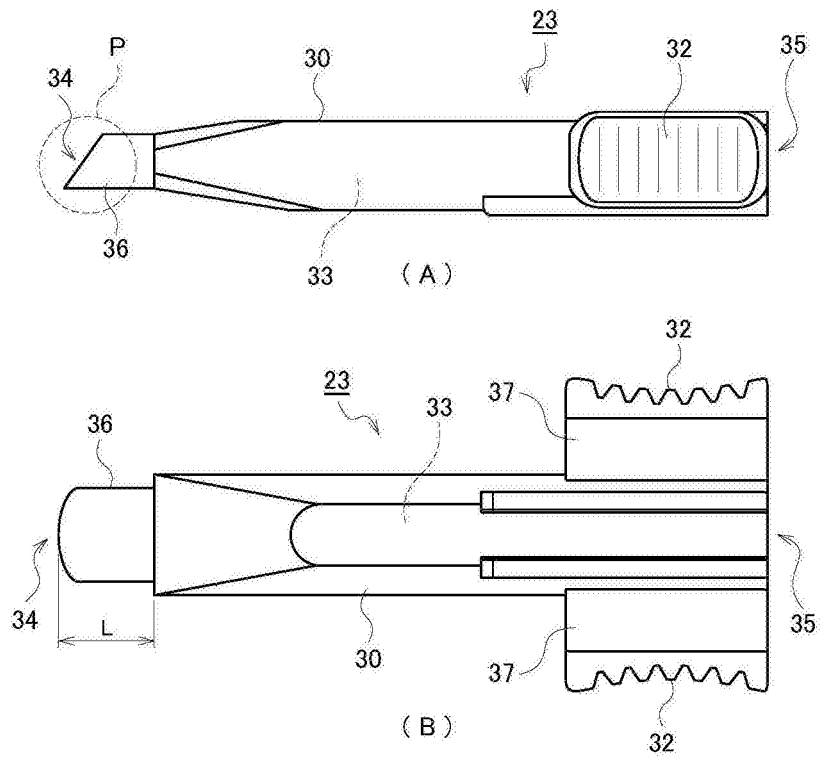
[図2]



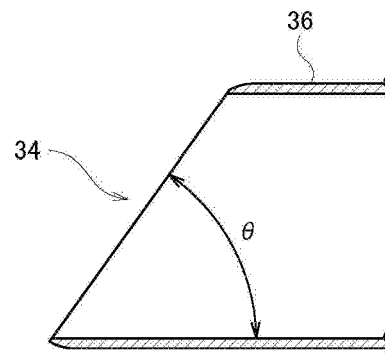
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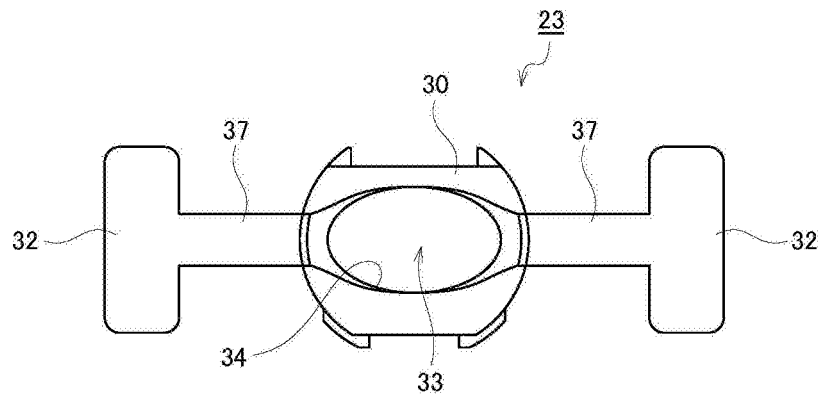
[図4]



[図5]

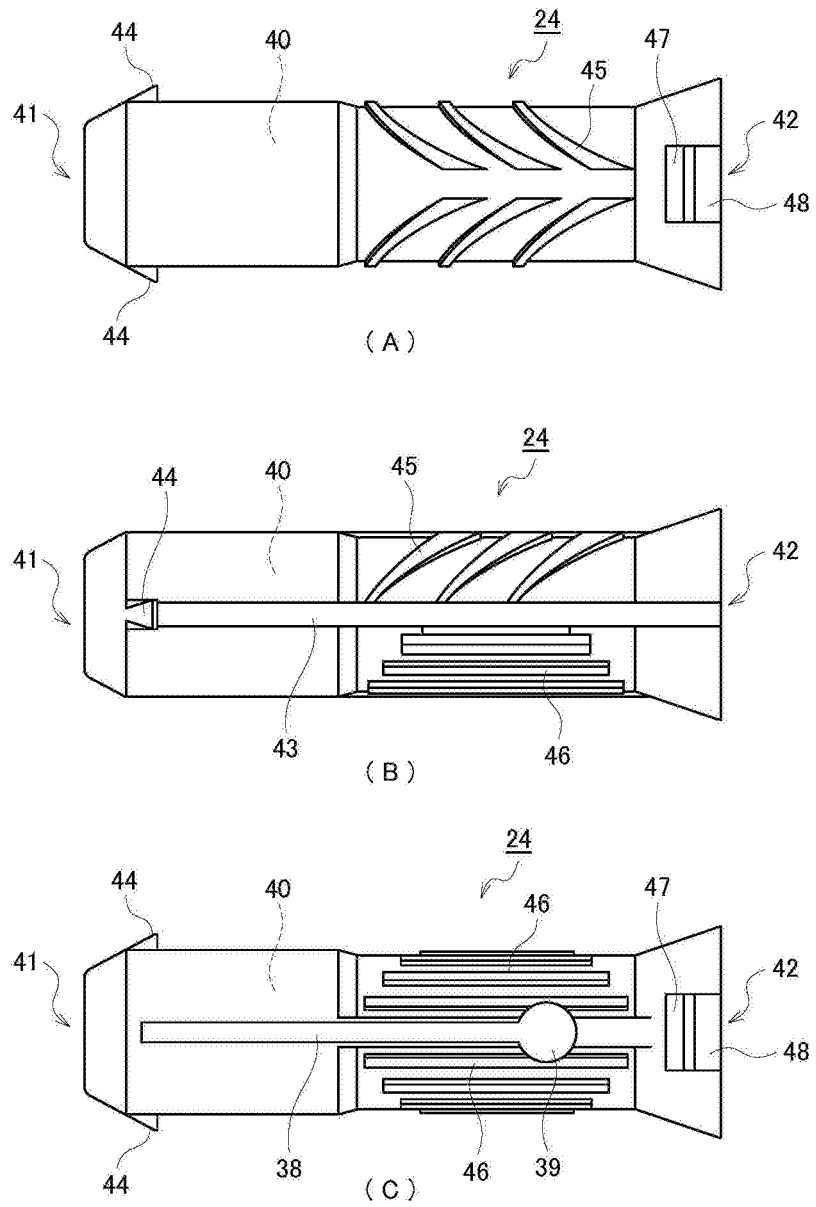


(A)

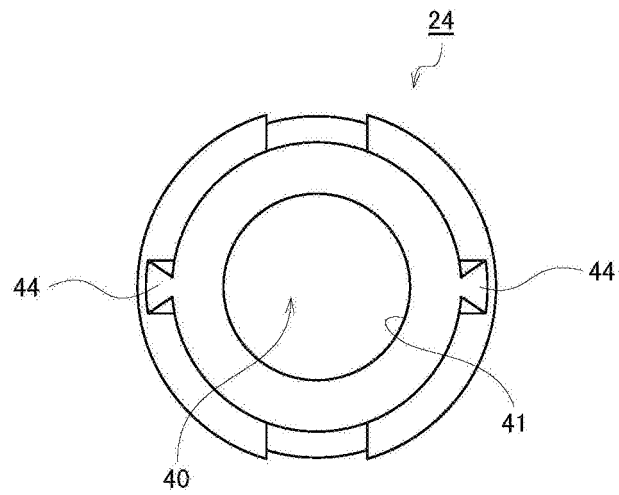


(B)

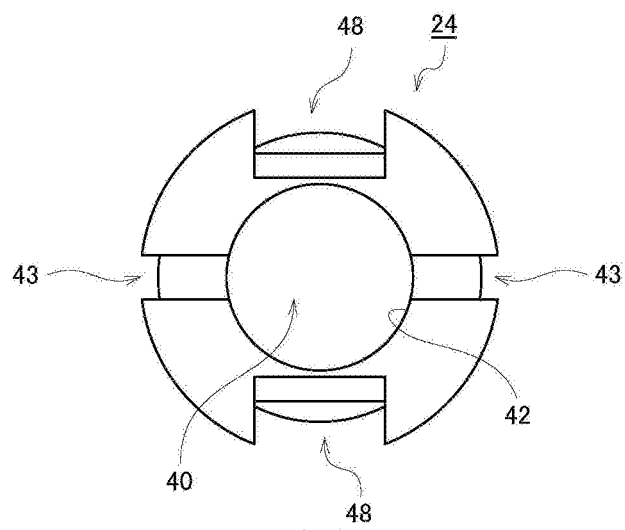
[図6]



[図7]

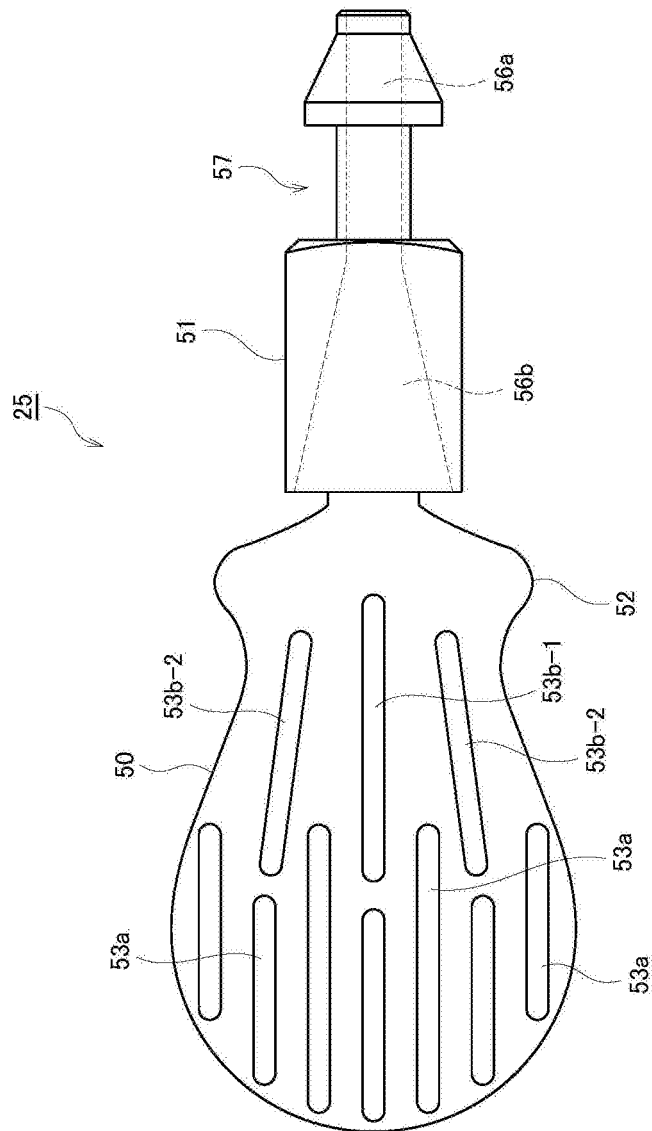


(A)

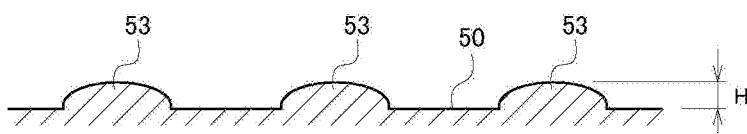


(B)

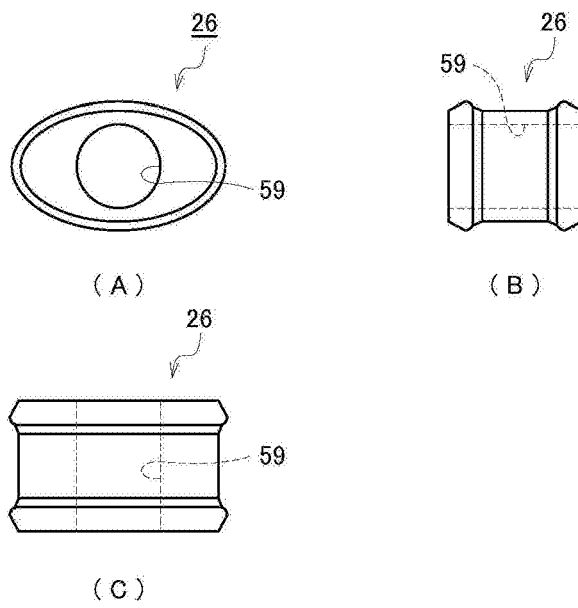
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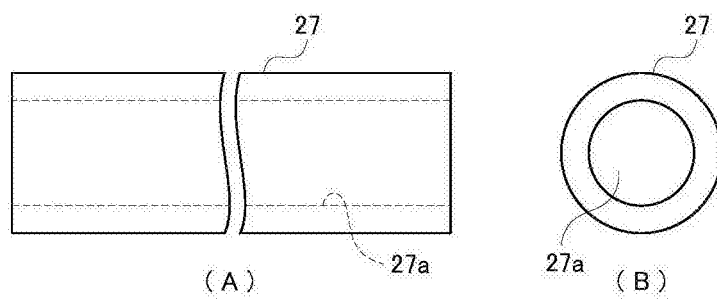
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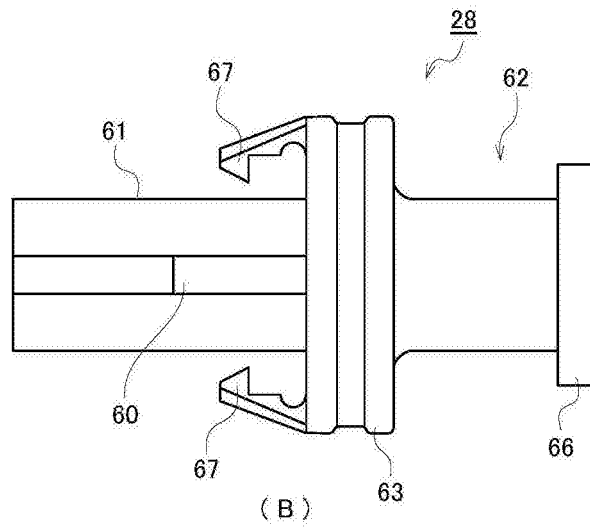
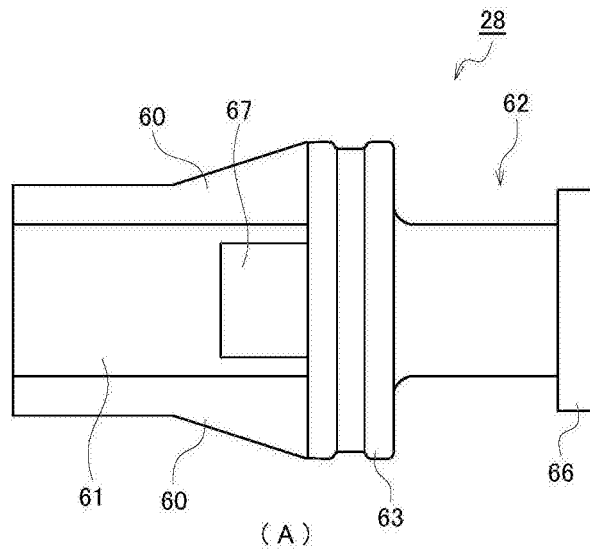
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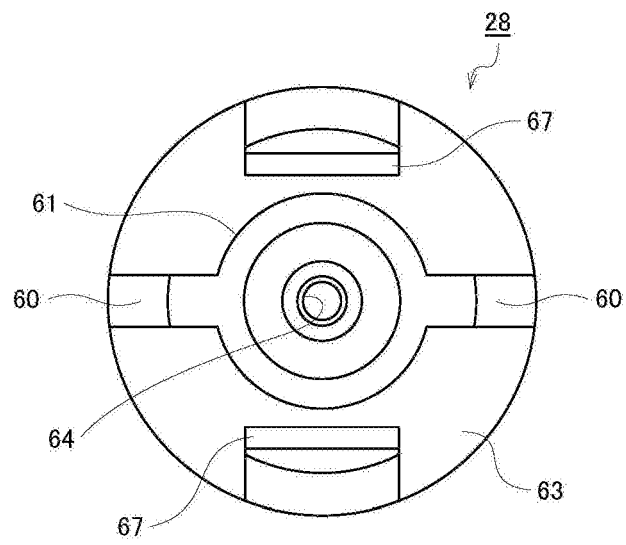
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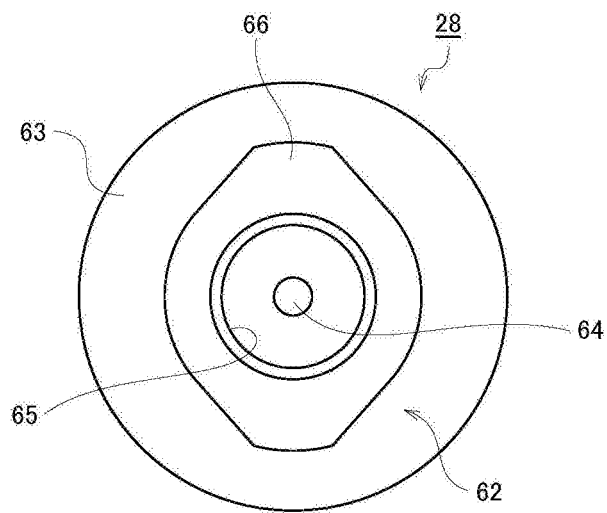
[図12]



[図13]

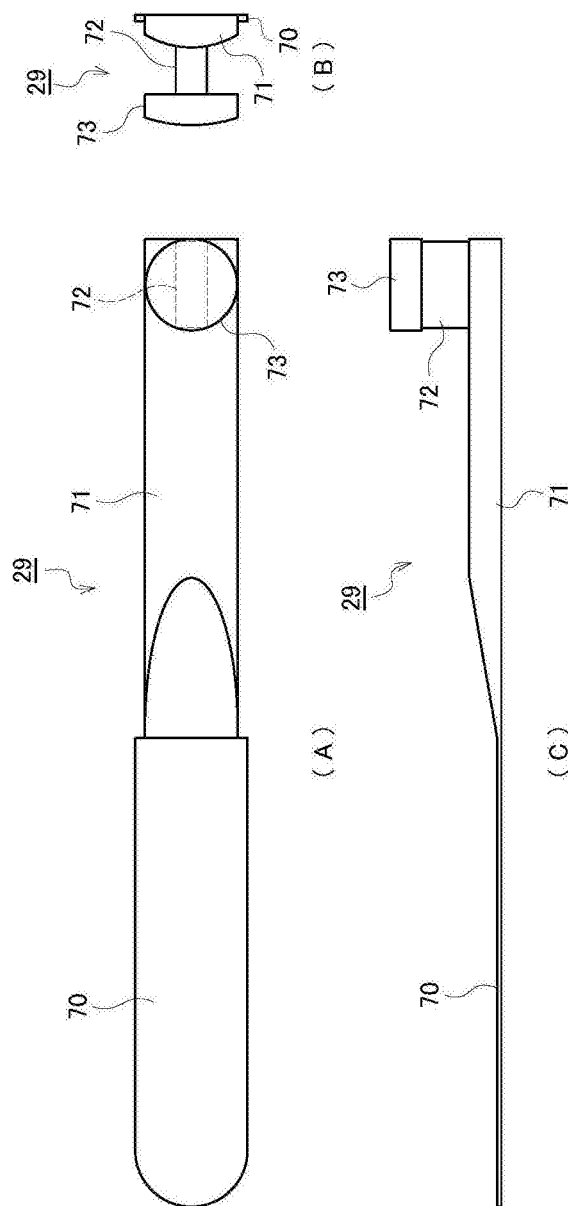


(A)

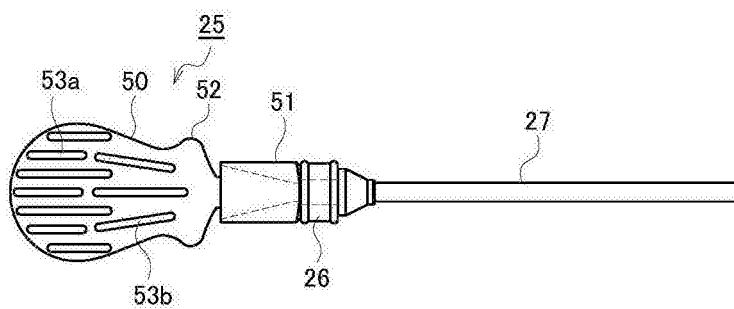


(B)

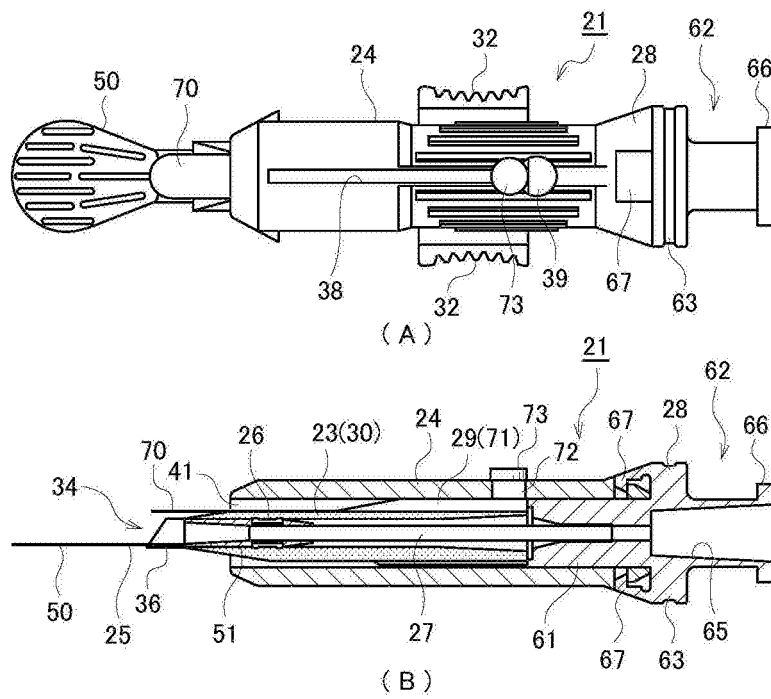
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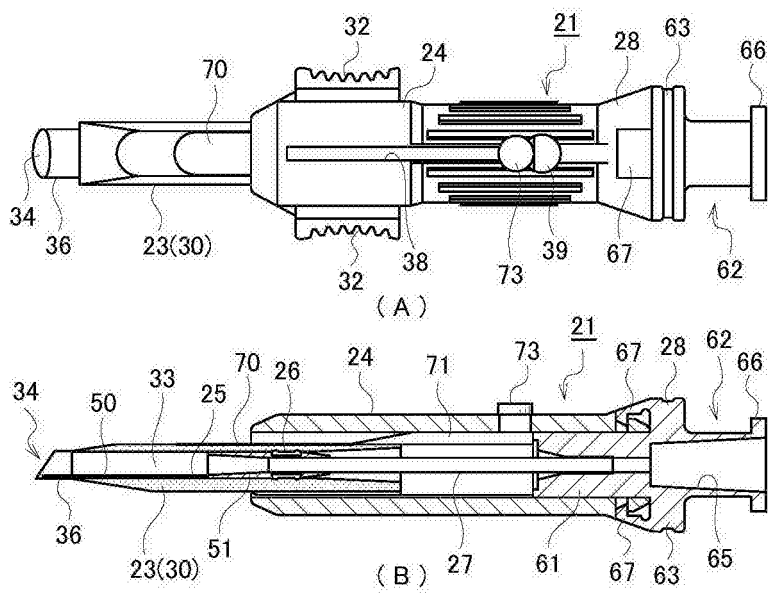
[図15]



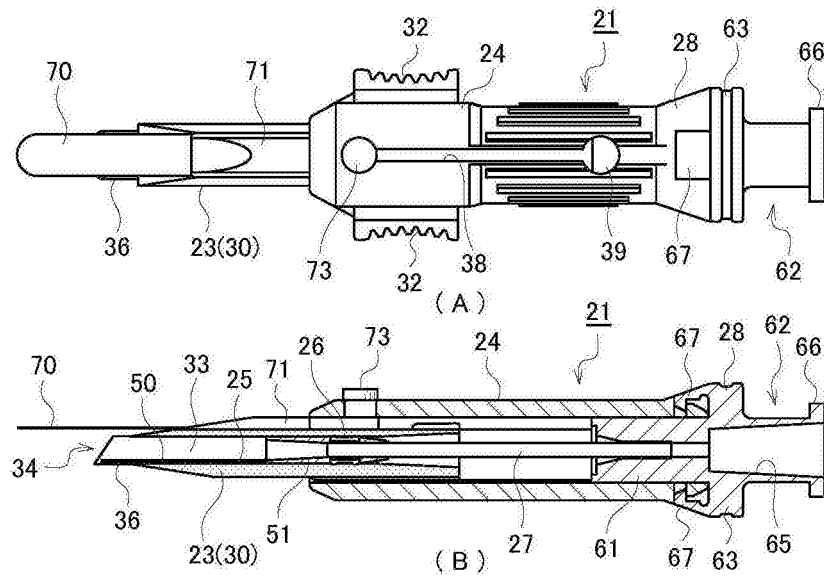
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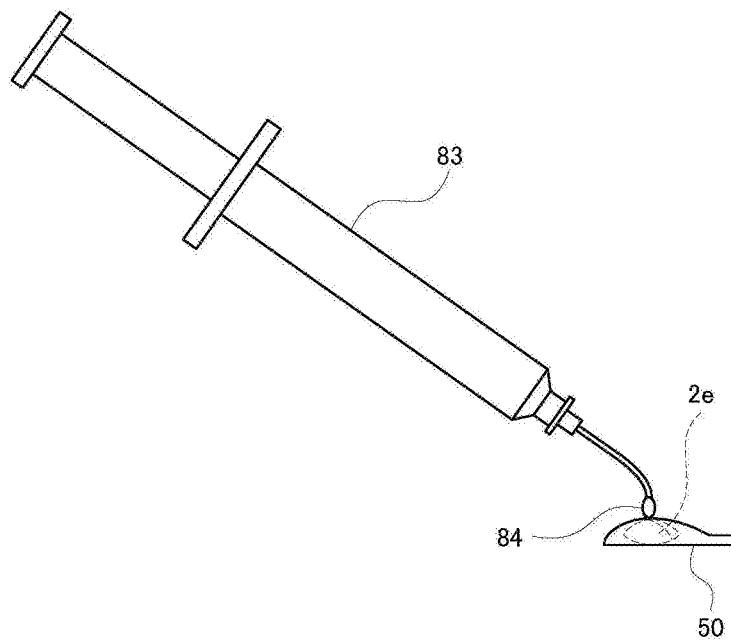
[図17]



[図18]

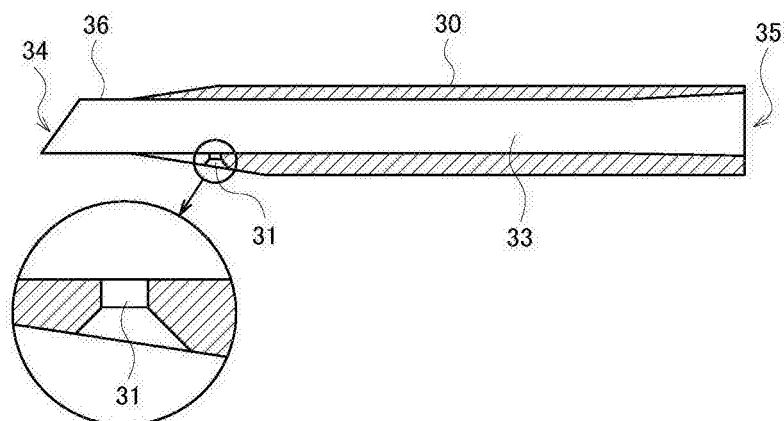


[図19]

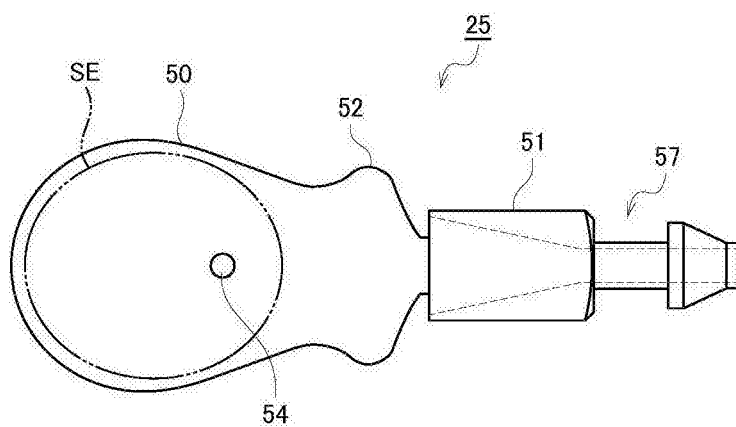


A cross-sectional view of a substrate 50. A thin layer 2e is disposed on the top surface of the substrate 50. A patterned layer 53 is disposed on the bottom surface of the substrate 50. The patterned layer 53 includes a first portion 53a and a second portion 53b, which are separated by a gap. A dashed line indicates the interface between the substrate 50 and the patterned layer 53. An arrow points to the left, indicating a direction of movement or force.

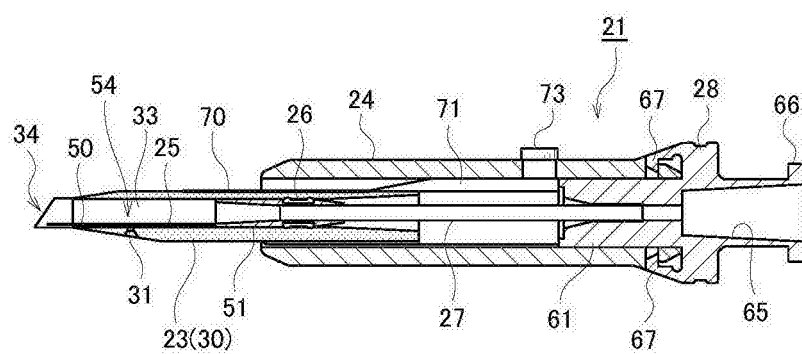
[図23]



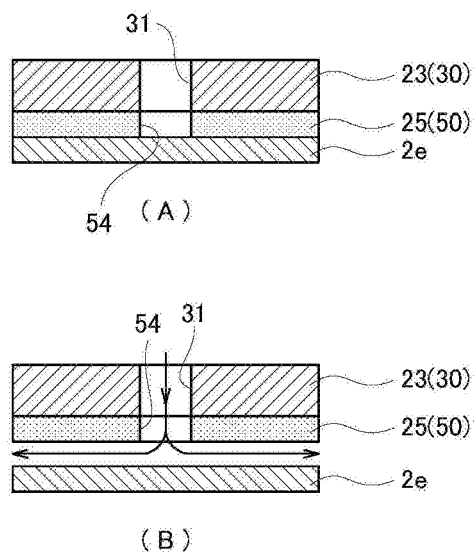
[図24]



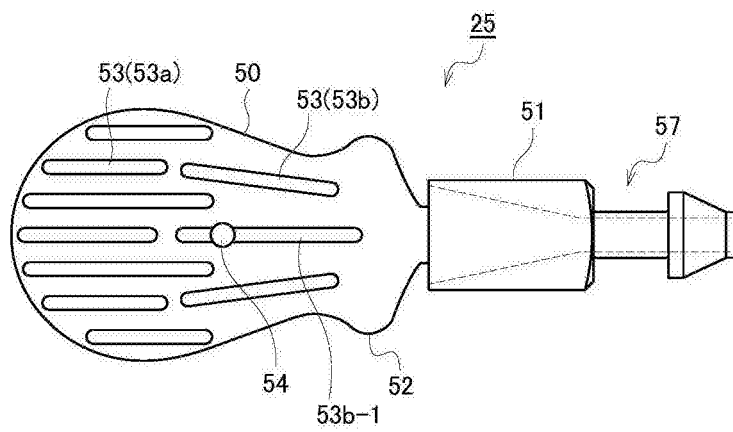
[図25]



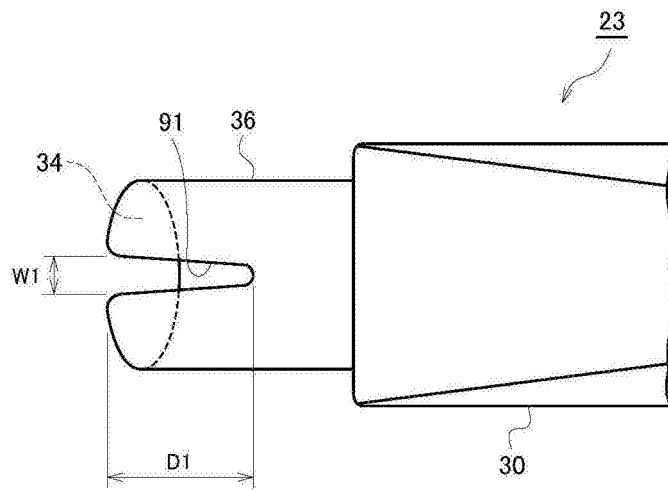
[図26]



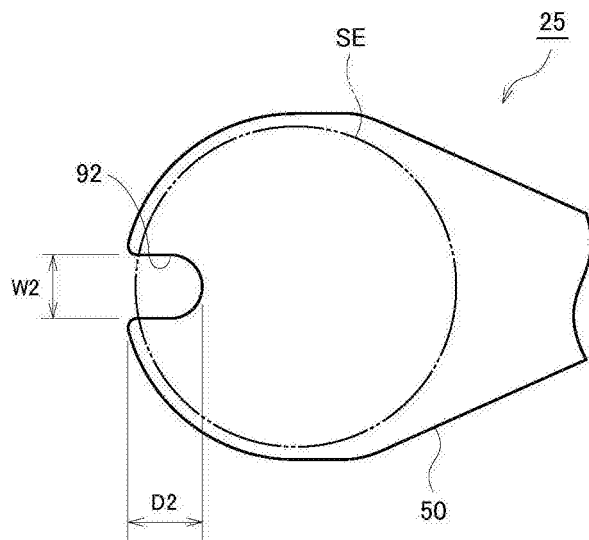
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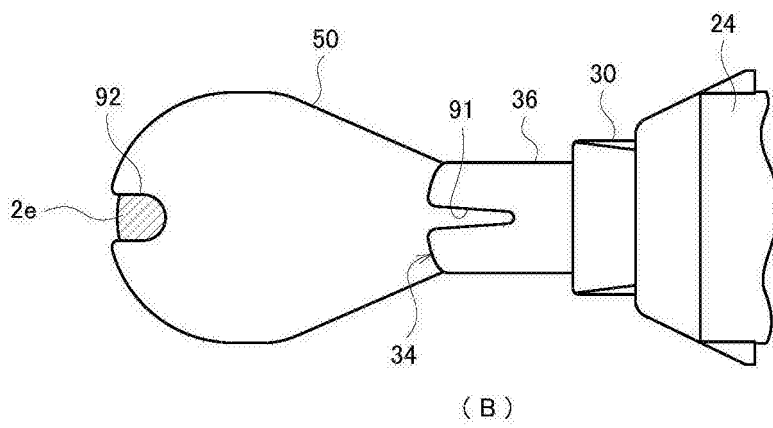
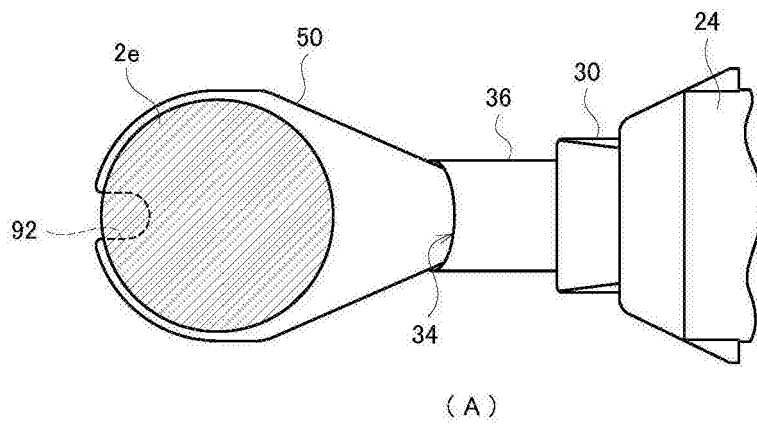
[図28]



[図29]

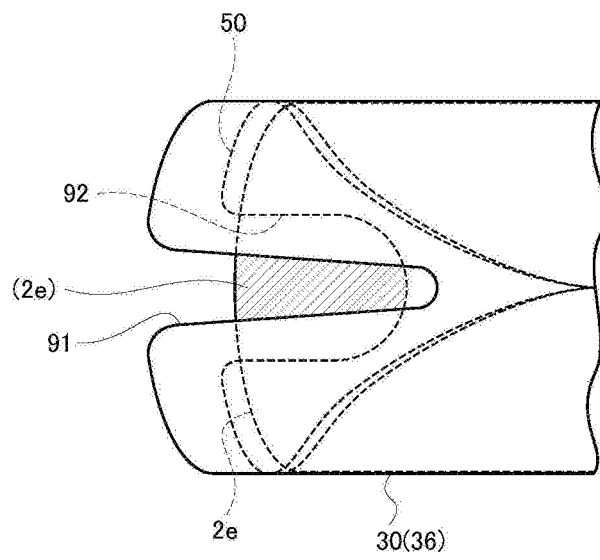


[図30]





[図32]



[図33]

